MAR 2 4 2003 THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Patel et al

Attorney Docket No.:

P06-US

Serial Number:

09/649,569

Group Art Unit:

1763

Filed:

August 28, 2000

Examiner:

A. Olsen

331103

For: APPARATUS AND METHOD FOR FLOW OF PROCESS GAS IN AN ULTRA-

CLEAN ENVIRONMENT

RESPONSE

Assistant Commissioner of Patents Date: March 17, 2003

Dear Sir or Madam:

This is a response to the Office Action mailed December 19, 2002. Please amend the above-identified application as follows:

IN THE CLAIMS:

Please amend the claims as follows:

Cancel claims 42-44 without prejudice or disclaimer.

Amend the following claims:

- 1. (Amended) Apparatus for etching a sample, said apparatus comprising:
 - (a) a source of etchant gas selected from a noble gas halide and a halogen halide;
 - (b) an etching chamber in communication with said source of etchant gas;
 - (c) a recirculation loop passing through said etching chamber; and
 - (d) a pump disposed within said recirculation loop for recirculating etchant gas along said recirculation loop.

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Response to Office Action (P06-US) - 8 pages Marked Copy of Claim Amendments - 15 pages Claims as Now Pending - 13 pages Return Receipt Postcard